YES Vapor Prime Oven SOP

1. Scope
   1. This document provides the procedure for operating the Yield LP III HMDS Vapor Prime Oven.

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1. Reference Documents

Referenced within this Document

* + 1. None

External Documents

* + 1. None

1. Equipment and/or Materials
   1. YES Vapor Prime Oven
   2. Wafer/Sample
   3. HMDS
2. Safety
   1. Follow all Nanofab safety procedures.
3. Setup Procedures
   1. Check the status of the system: See .
      * 1. Vacuum Gauge: <100 Torr
        2. Temp. ~150 C
        3. HMDS in flask
        4. Vacuum pump off
   2. Turn on vacuum pump. See .
   3. Press the black START button. This will vent the system for 5 minutes. See .



Power Switch

Figure , Vacuum Pump

1. Film Deposition Procedures
   1. Pull the door open and insert wafers.
   2. Close the door. This may require a bit of force.
   3. Press the black START button again.

NOTE: This will start pump down and deposition process. The total time is ~30 minutes.

* 1. An alarm will sound when the run is finished.
  2. Press the black START button again to vent the system.
  3. Pull the door open and remove samples.
  4. Close the door and press the black START button.
  5. Once the vacuum gauge reads lower than 100 Torr, press the red RESET button. See .

NOTE: This will stop the system. Make sure this is done before the next step or it will begin a nitrogen backfill.

* 1. Turn off the vacuum pump.



HMDS Flask

Temperature

Vacuum Gauge

Start Button

Reset Button

Figure , Control Panel

1. Revision History

|  |  |  |  |
| --- | --- | --- | --- |
| Rev | Date | Originator | Description of Changes |
| 1 | 14 Jan 2010 | Sam Bell |  |
|  |  |  |  |